## **PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

DAVID A. PALSULICH ET AL.

APPLICATION NO.:

10/636,021

FILED:

For:

AUGUST 6, 2003

MICROFEATURE WORKPIECE

PROCESSING SYSTEM FOR, E.G.,

SEMICONDUCTOR WAFER ANALYSIS

EXAMINER: MAHMOUD

**DAHIMENE** 

ART UNIT:

1792

CONF. NO:

1017

## Comments on Statement of Reasons for Allowance

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In the Notice of Allowability mailed March 17, 2010, the Examiner allowed claims 1–9, 19 and 21-28. Although the undersigned attorney agrees with the Examiner's conclusion that these claims are allowable, the undersigned attorney notes that the claims may be allowable for reasons other than those identified by the Examiner and does not concede that the Examiner's characterizations of the terms of the claims and the prior art are correct.

Date: June 16, 2010 Respectfully submitted, Perkins Coie LLP

Chen Liang

Registration No. 51,945

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